OPTIMAL ONE-WAFER SCHEDULING OF SINGLE-ARM MULTI-CLUSTER TOOLS WITH TREE-LIKE TOPOLOGY

CROSS-REFERENCE TO RELATED APPLICATIONS

[0001] This application claims the benefit of U.S. Provisional Patent Application No. 62/221,035, filed on Sep. 20, 2015, which is incorporated by reference herein in its entirety.

LIST OF ABBREVIATIONS

[0002] BM buffer module
[0003] CTC cluster-tool-chain
[0004] FP fundamental period
[0005] LL loadlock
[0006] PM process module
[0007] PN Petri net
[0008] R robot
[0009] ROPN resource-oriented PN

BACKGROUND

Field of the Invention

[0010] The present invention generally relates to scheduling a tree-like multi-cluster tool. In particular, the present invention relates to a method for scheduling this multi-cluster tool to thereby generate an optimal one-wafer cyclic schedule.

LIST OF REFERENCES

[0011] There follows a list of references that are occasionally cited in the specification. Each of the disclosures of these references is incorporated by reference herein in its entirety.

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